

B. Specification

Please amend the paragraph at page 14, lines 5-14, as follows:

--wherein R_9 represents a substituent group on the aromatic ring, R_9 is selected from ~~[[thg]]~~ the group consisting of H, halogen, CN, NO_2 , COOR_{10} , SO_2R_{11} (wherein R_{10} represents any one selected from the group consisting of H, Na, K, CH_3 and C_2H_5 , and R_{11} represents any one selected from the group consisting of OH, ONa, OK, halogen, OCH_3 and OC_2H_5), CH_3 , C_2H_5 , C_3H_7 , $(\text{CH}_3)_2\text{-CH}$ and $(\text{CH}_3)_3\text{-C}$, and in a case where there exist a plurality of units, R_9 may be different for each unit;--

Please amend the paragraph at page 15, lines 2-9, as follows:

--wherein R_{12} is selected from ~~[[thg]]~~ the group consisting of H, halogen, CN, NO_2 , COOR_{13} , SO_2R_{14} (wherein R_{13} represents any one selected from the group consisting of H, Na, K, CH_3 and C_2H_5 , and R_{14} represents any one selected from the group consisting of OH, ONa, OK, halogen, OCH_3 and OC_2H_5), CH_3 , C_2H_5 , C_3H_7 , $(\text{CH}_3)_2\text{-CH}$ and $(\text{CH}_3)_3\text{-C}$, and in a case where there exist a plurality of units, R_{12} may be different for each unit; and--

Please amend the paragraph at page 25, lines 5-24, as follows:

--As microorganisms used for the production method of the present invention, any species of microorganisms may be used, as long as they have an ability to satisfy the above described conditions. Among them, microorganisms belonging to

Pseudomonas species are desirable. Specific examples of preferred species include *Pseudomonas cichorii*, *Pseudomonas putida*, *Pseudomonas fluorescens*~~*fluorescens*~~^{*fluorescens*}, *Pseudomonas oleovorans*, *Pseudomonas aeruginosa*, *Pseudomonas stutzeri*, and *Pseudomonas jessenii*. More specifically, examples of a suitable strain include *Pseudomonas cichorii* YN2 (FERM BP-7375), *Pseudomonas cichorii* H45 (FERM BP-7374), and *Pseudomonas jessenii* P161 (FERM BP-7376). These three types of strains were deposited on November 20, 2000 at the International Patent Organism Depositary (IPOD) of National Institute of Advanced Industrial Science and Technology (AIST), Tsukuba Central 6, 1-1, Higashi 1-chome, Tsukuba-shi, Ibaraki-ken 305-8566, Japan, and they are described in U.S. Patent 6,586,562.--